

FIG.1A

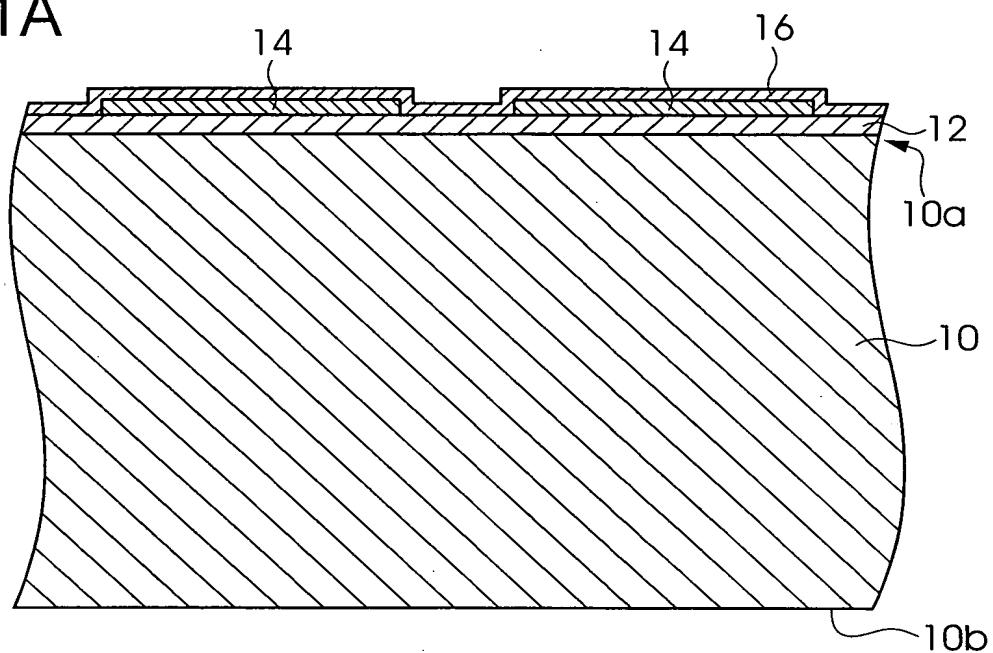


FIG.1B

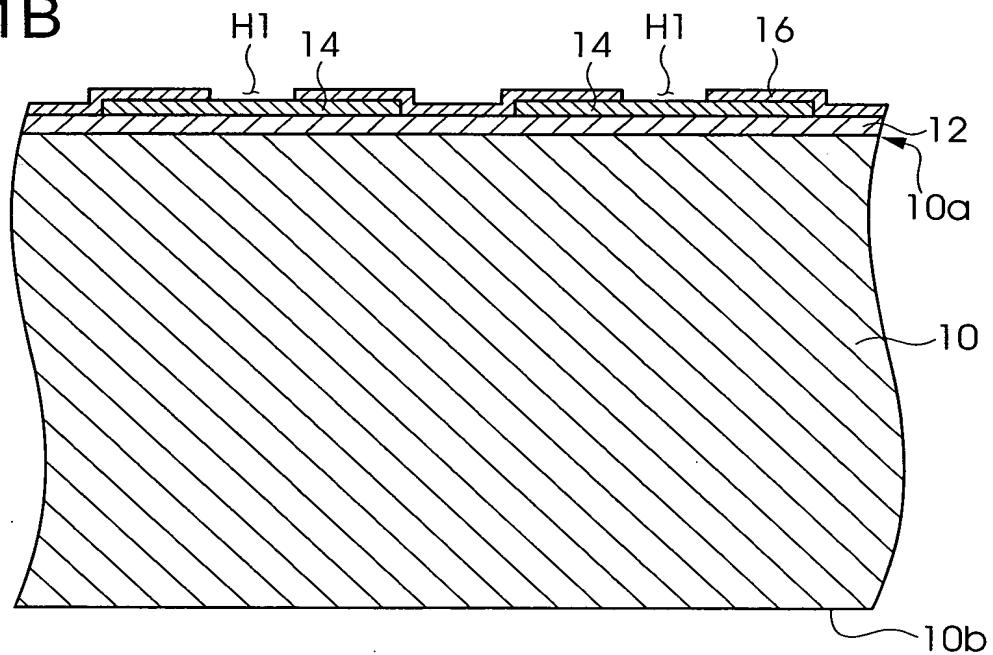


FIG.2A

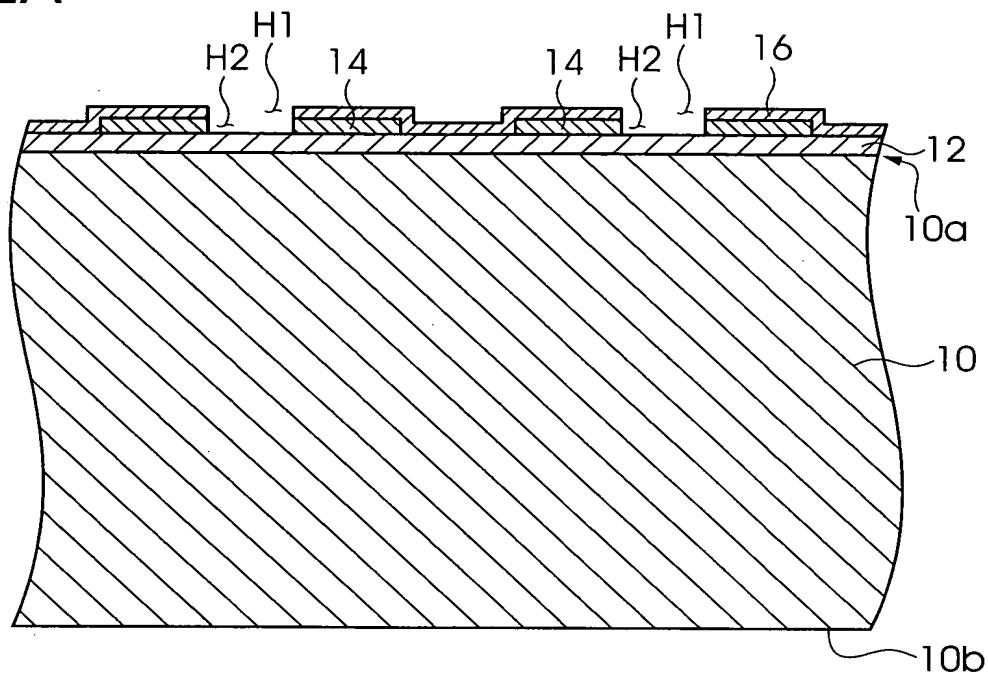


FIG.2B

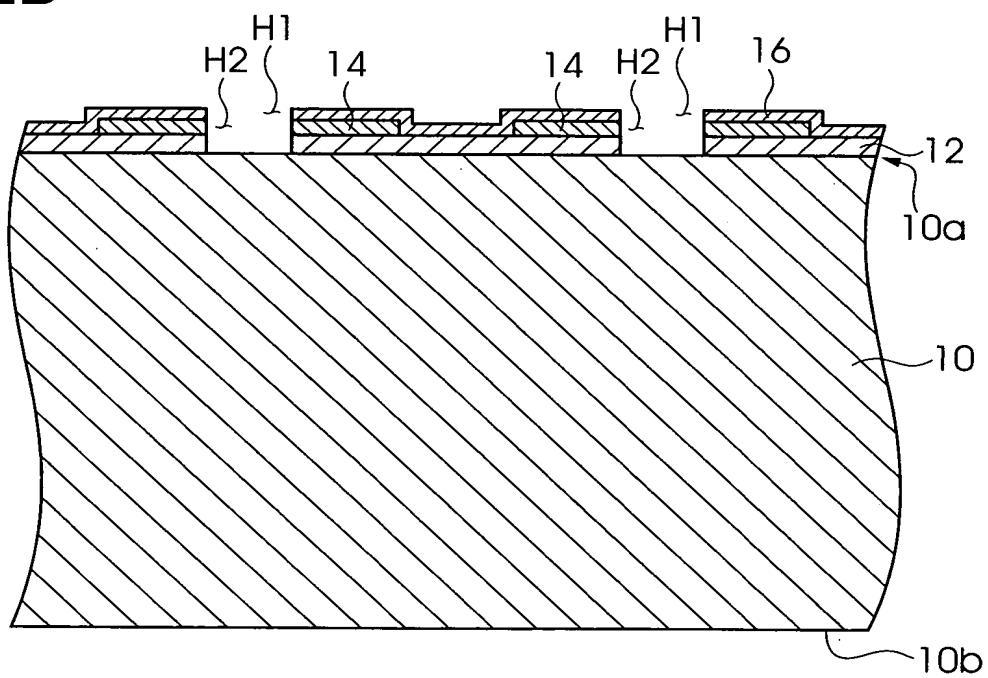


FIG.3A

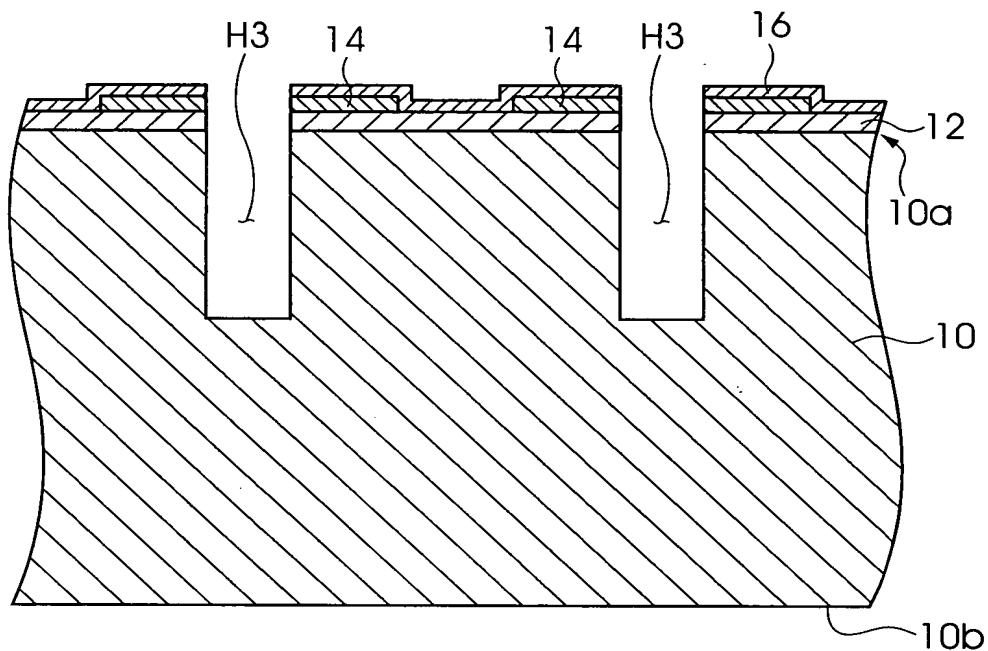


FIG.3B

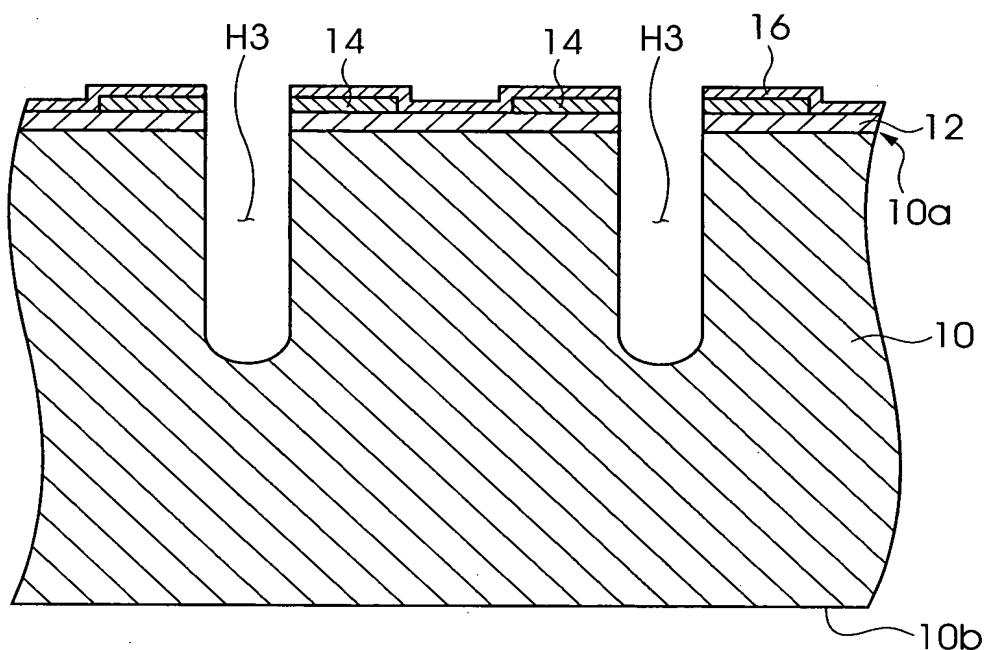


FIG.4A

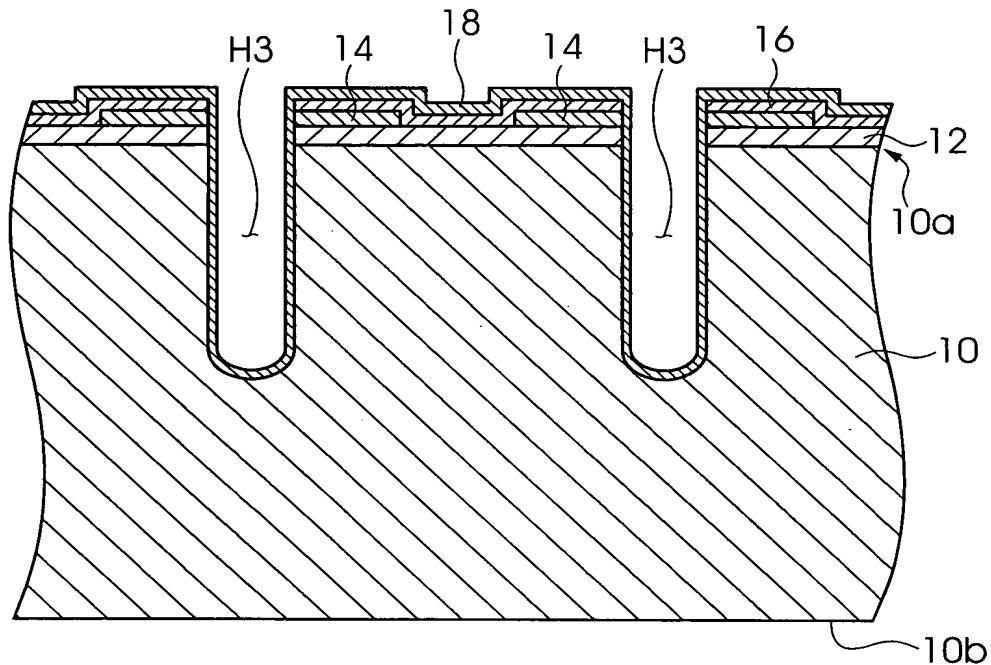
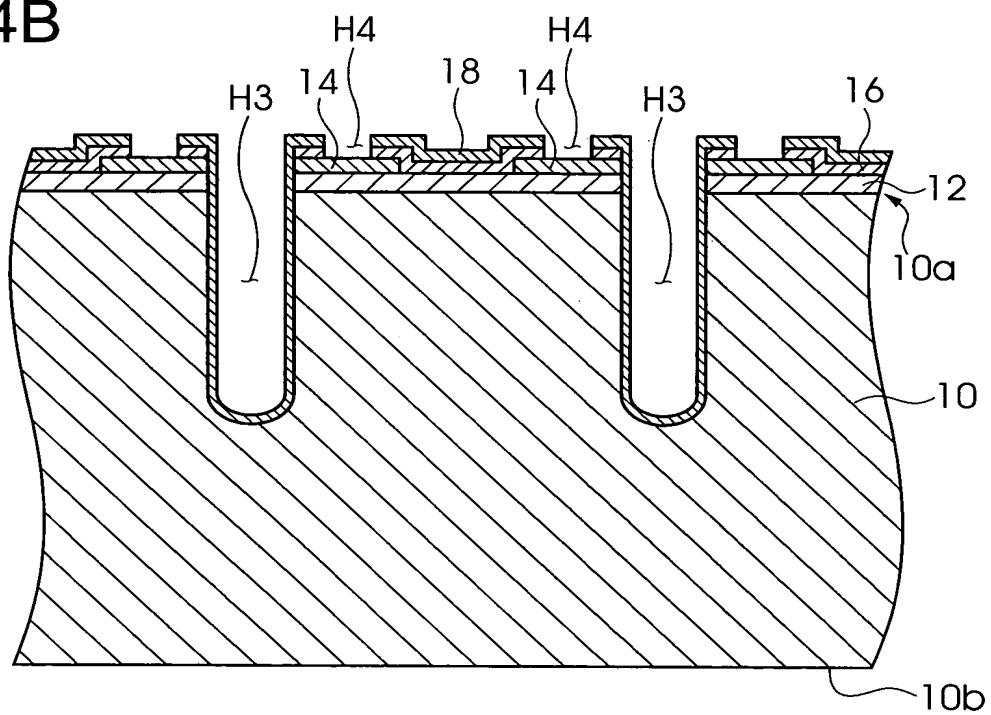
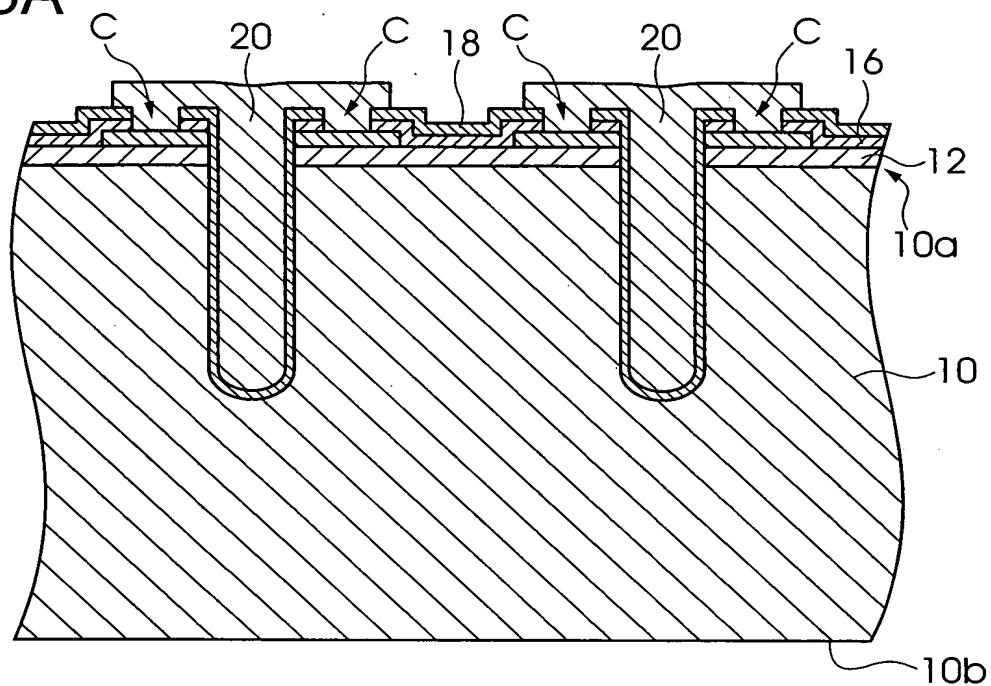


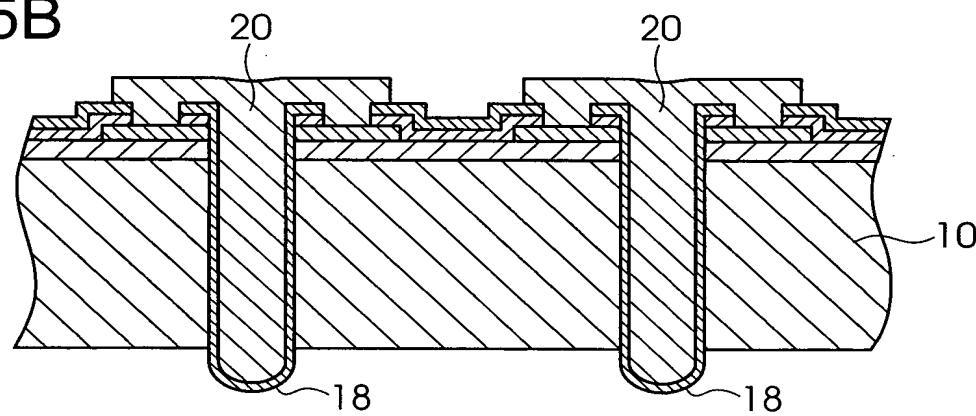
FIG.4B



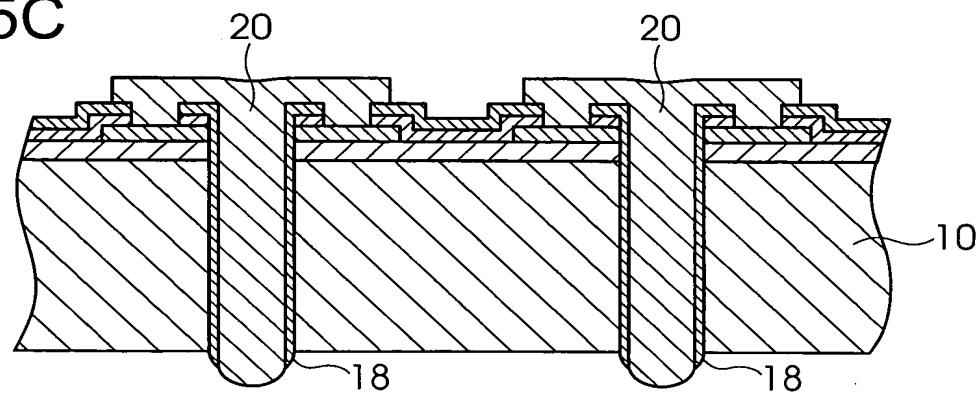
**FIG.5A**



**FIG.5B**



**FIG.5C**



Title: MANUFACTURING METHOD FOR SEMICONDUCTOR DEVICE,  
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FIG.6

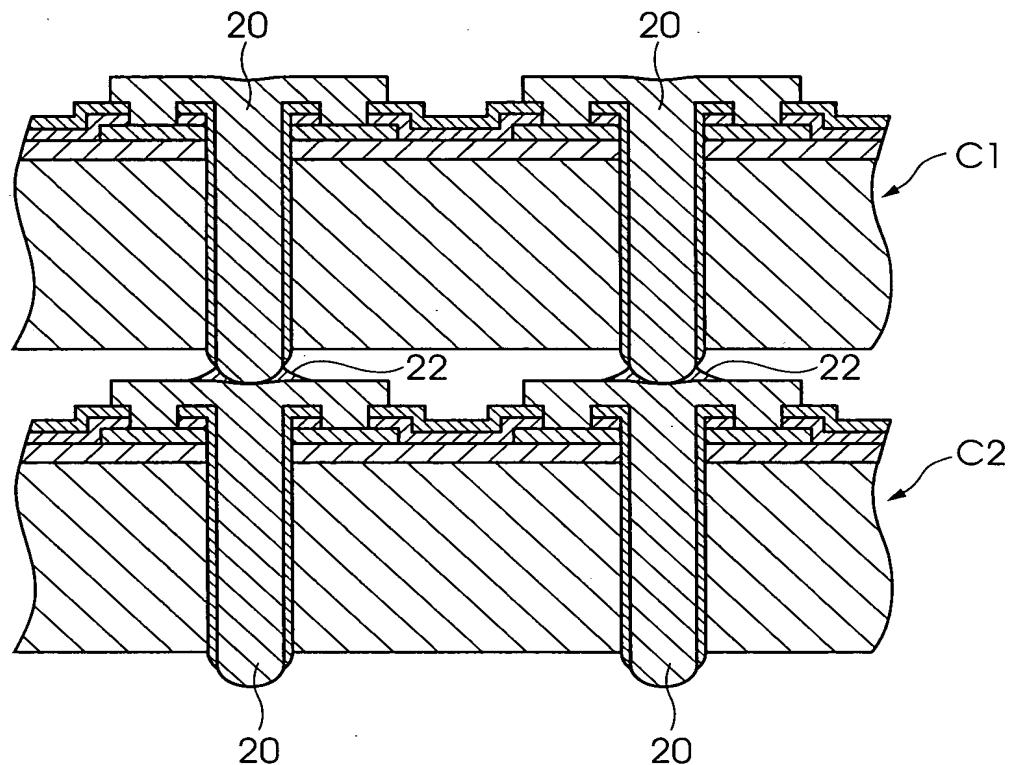


FIG.7A

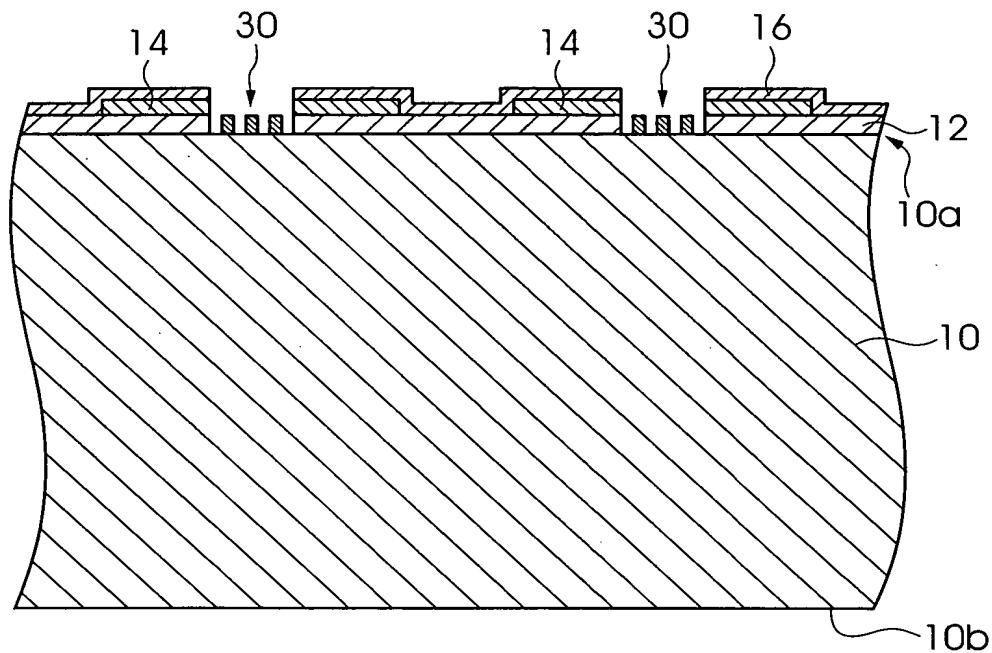
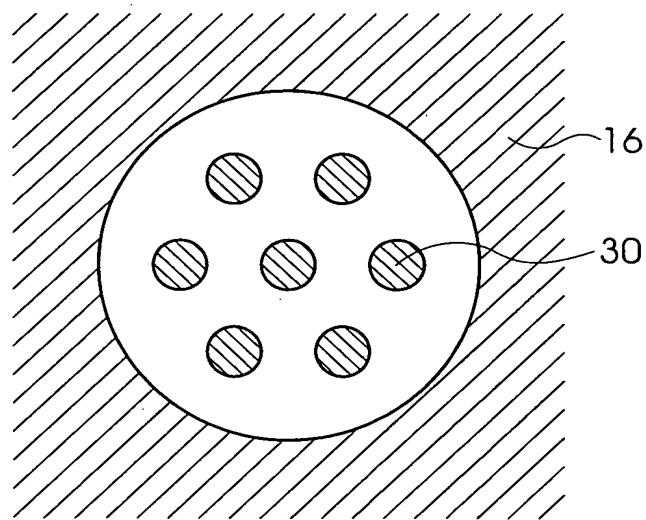
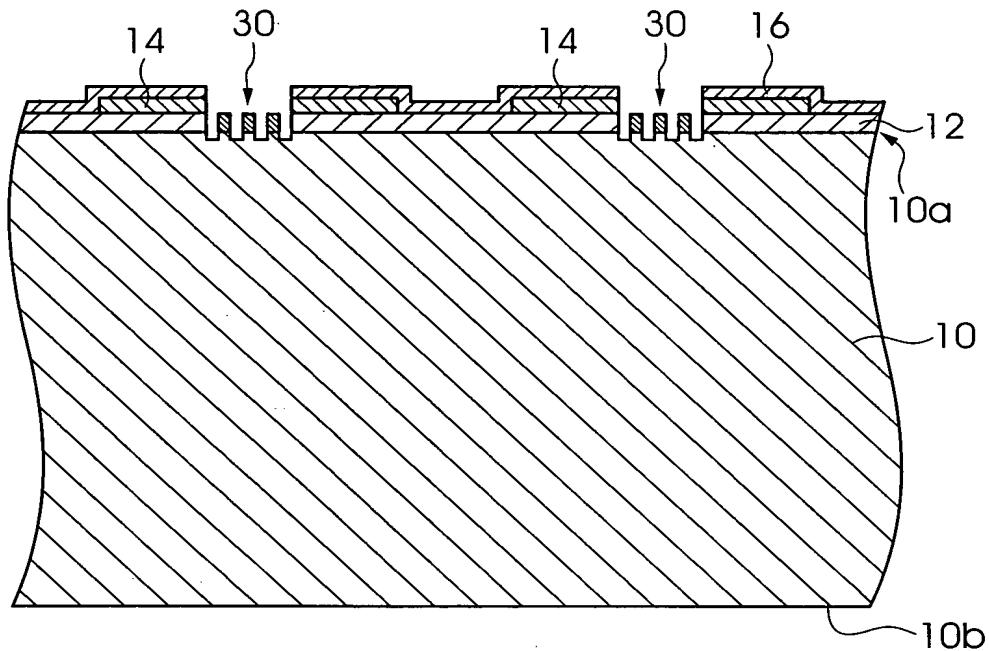


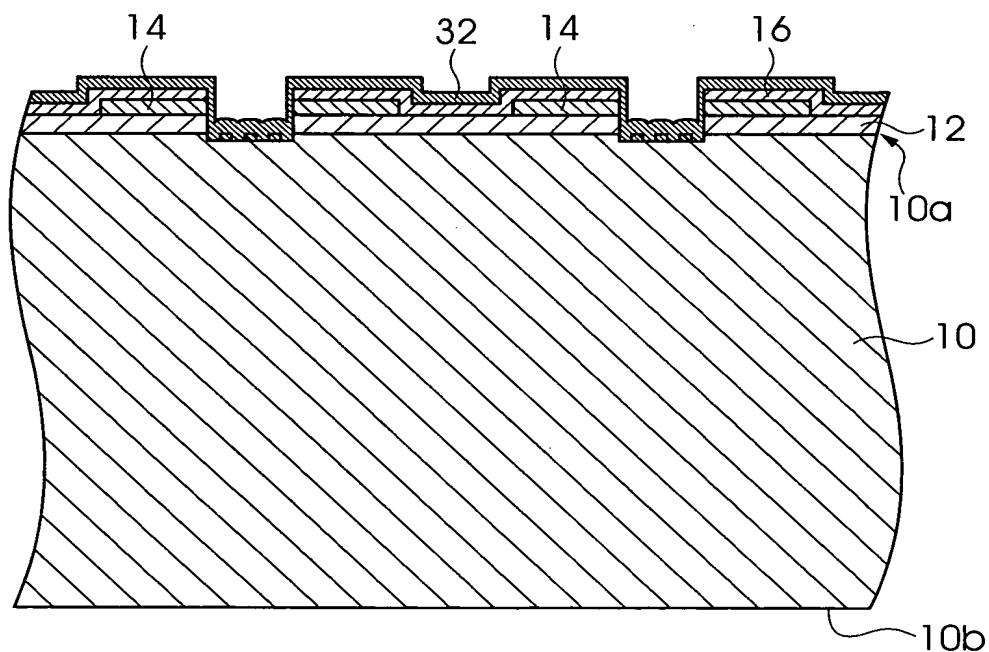
FIG.7B



**FIG.8A**



**FIG.8B**



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FIG.9A

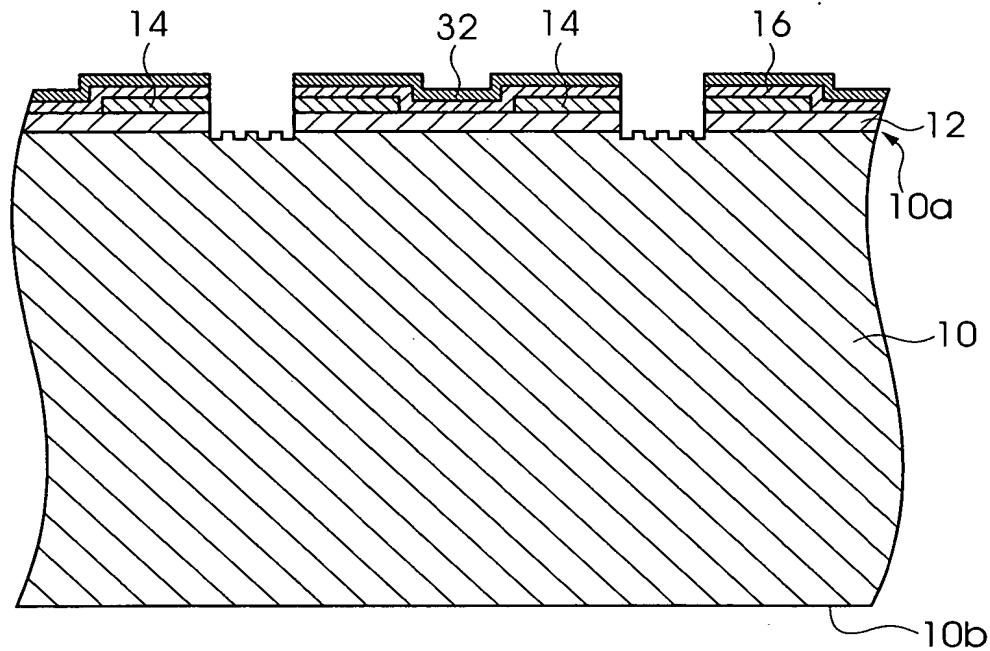


FIG.9B

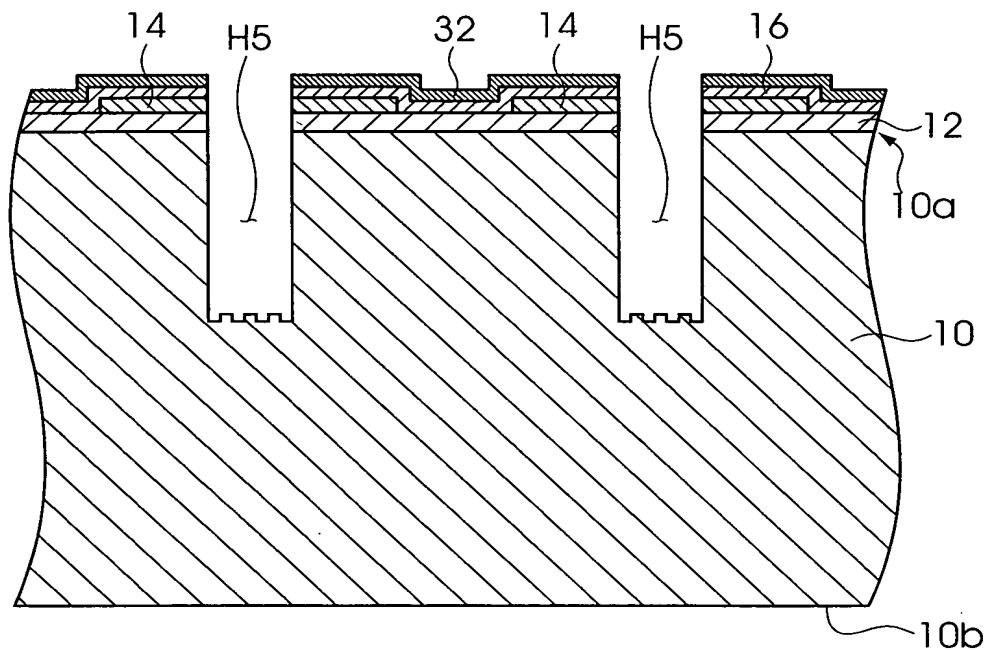


FIG.10A

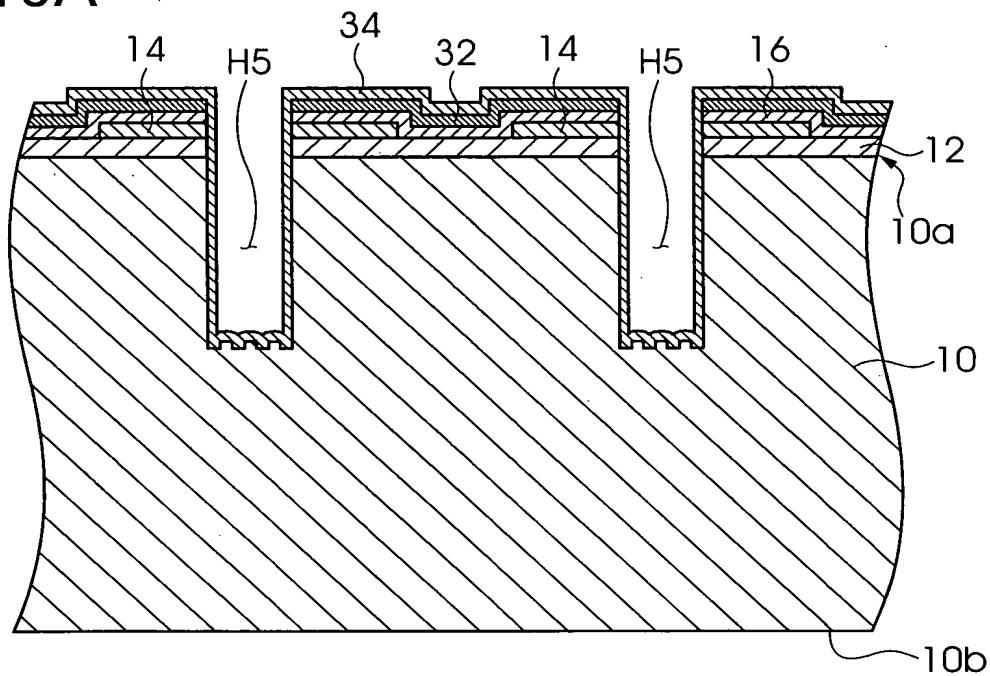
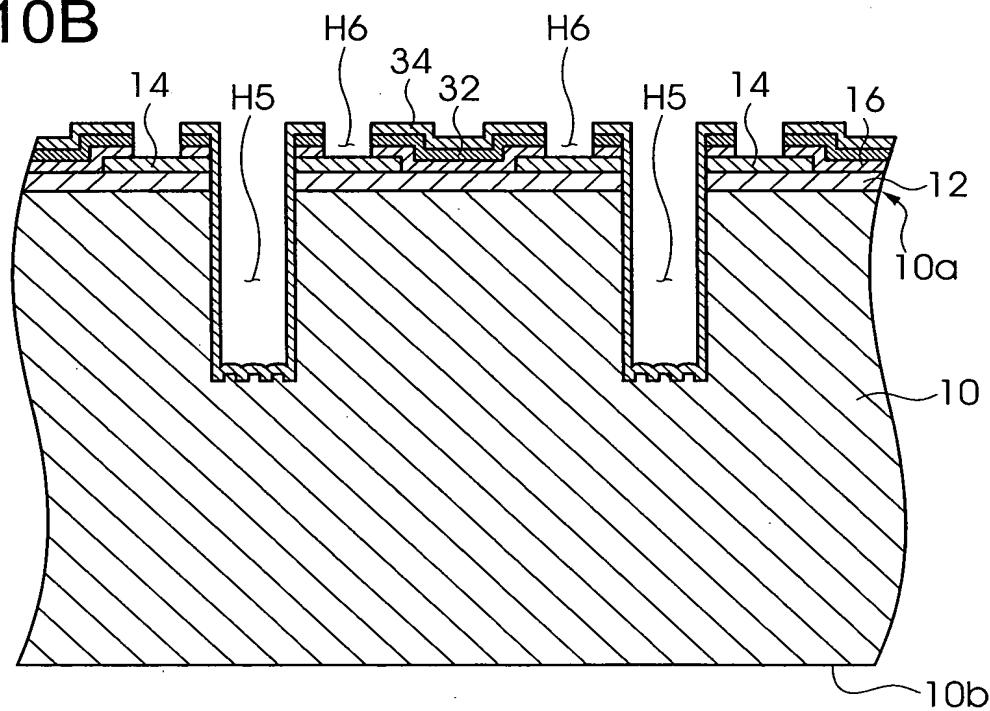


FIG.10B



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FIG.11A

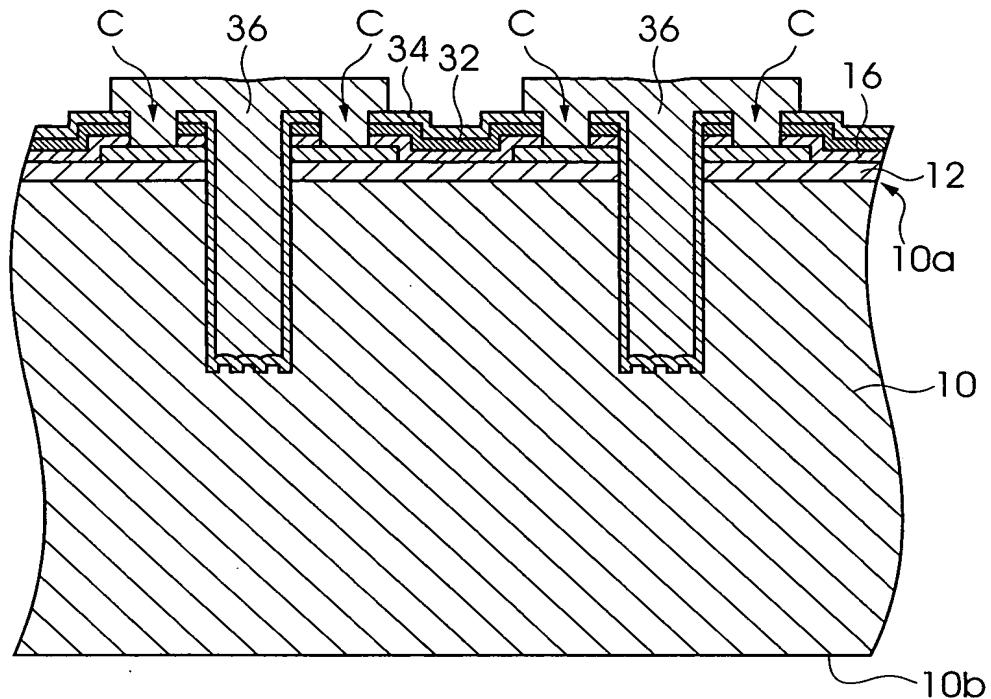


FIG.11B

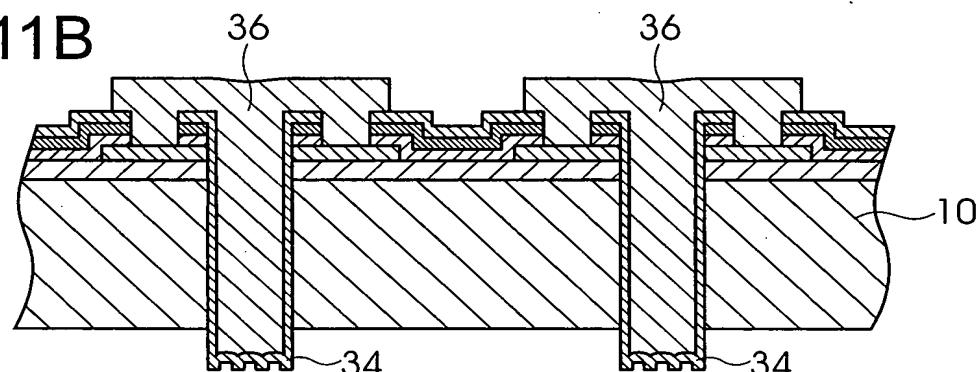


FIG.11C

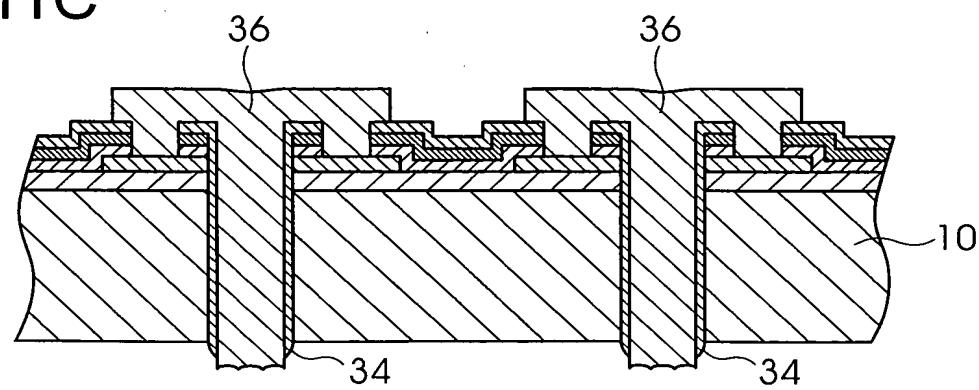
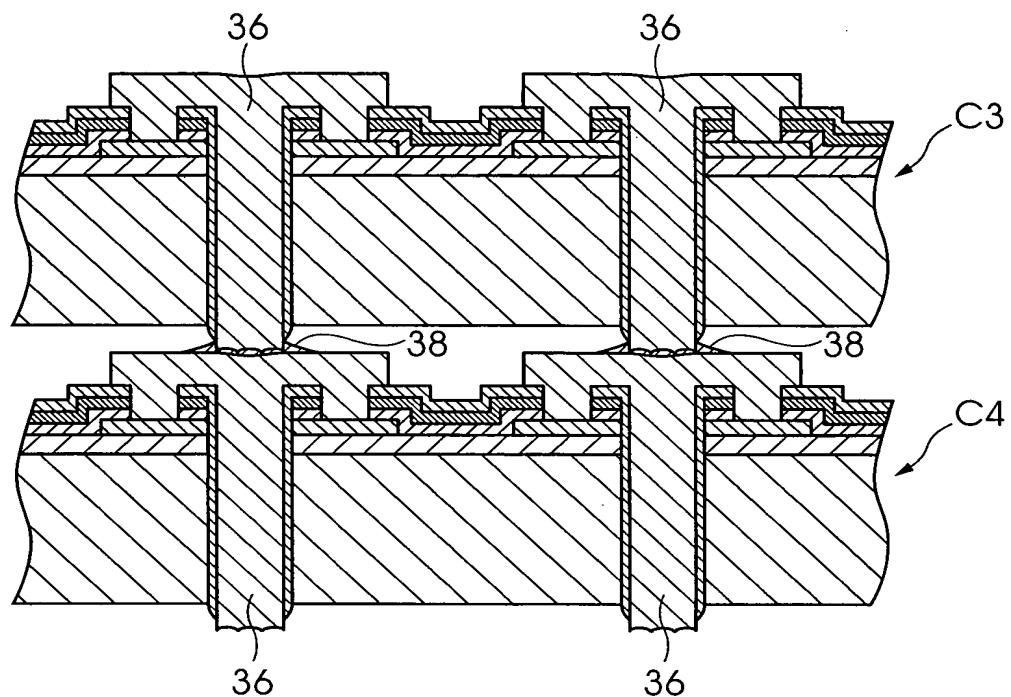


FIG.12



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FIG.13A

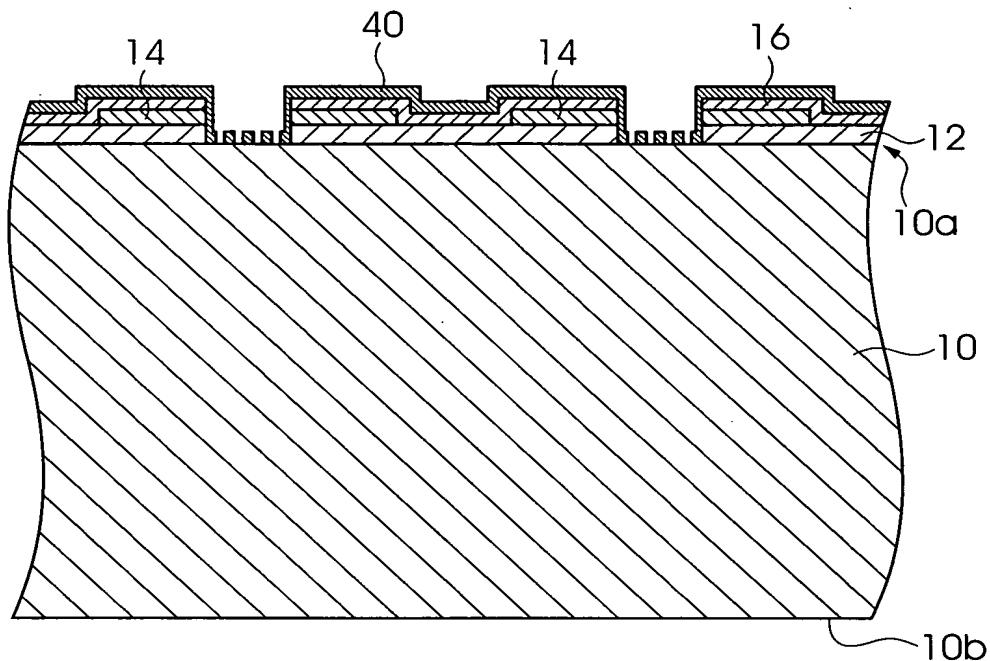


FIG.13B

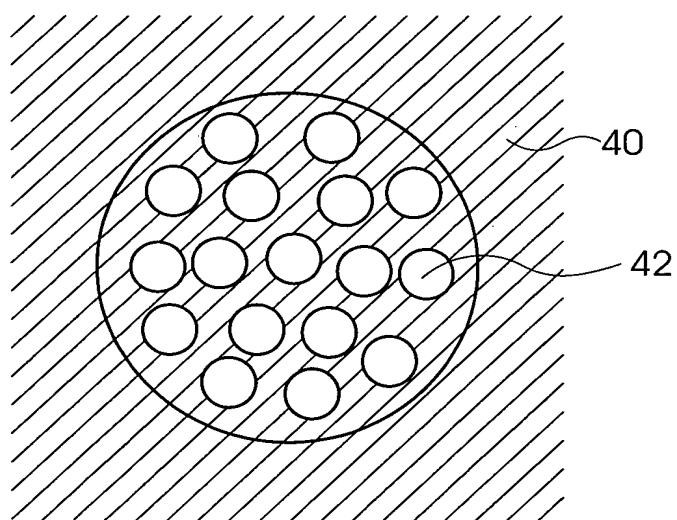


FIG.14A

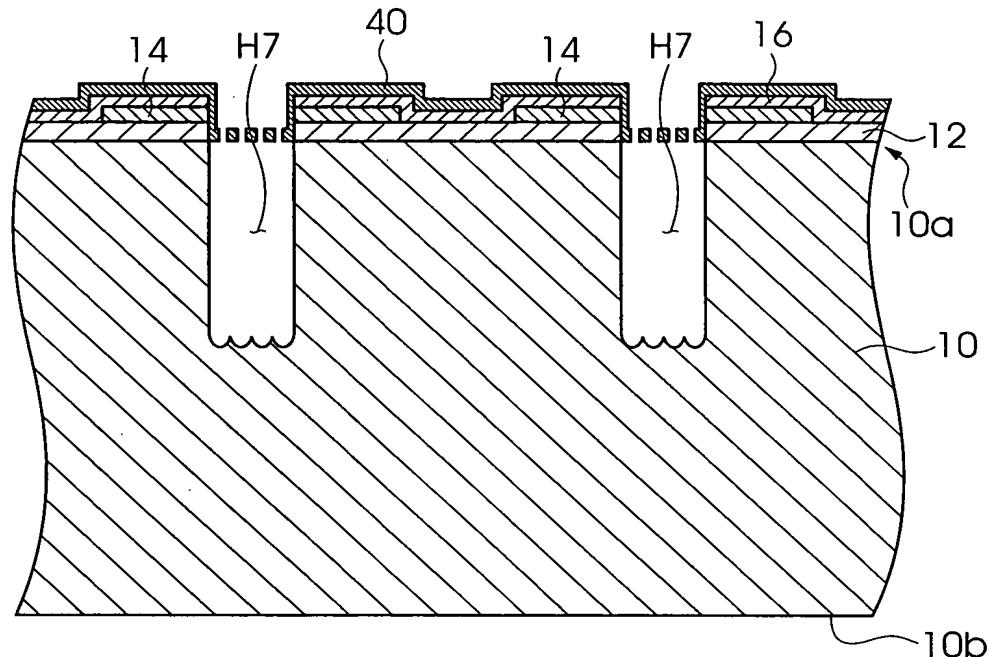


FIG.14B

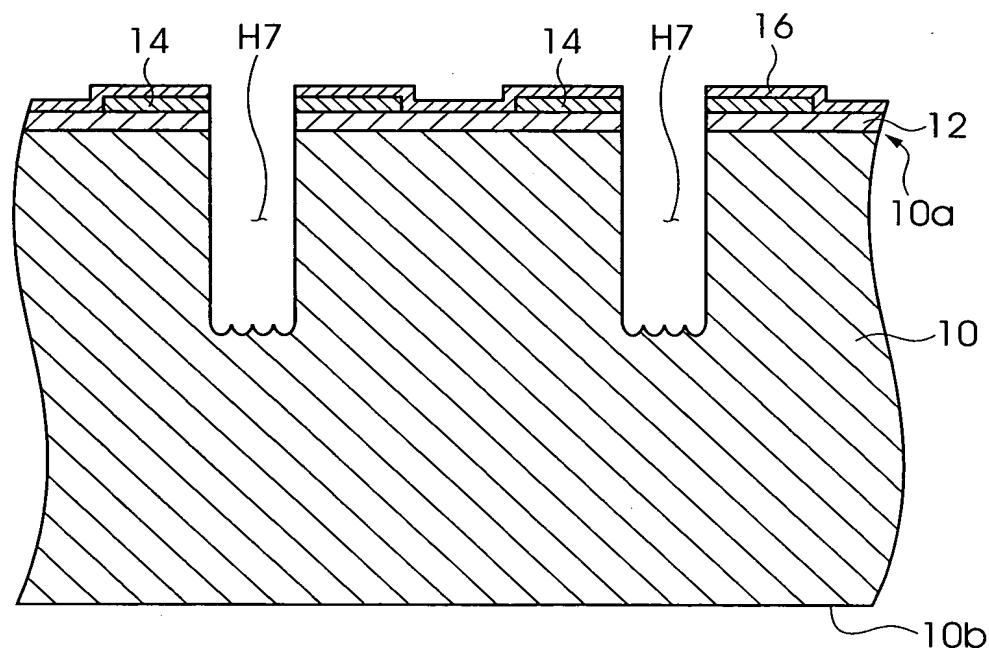


FIG.15A

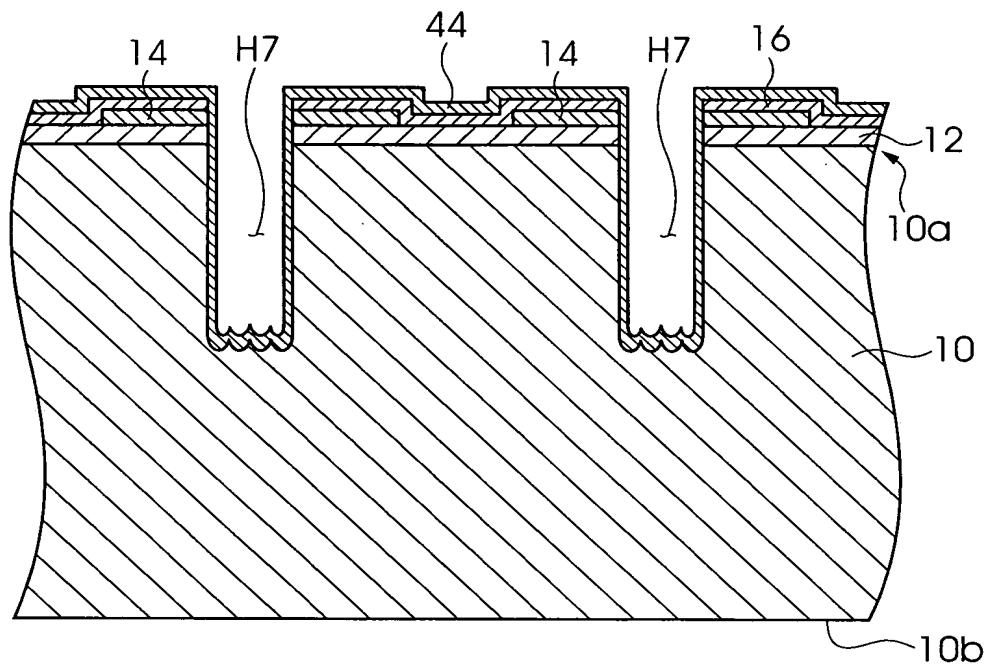
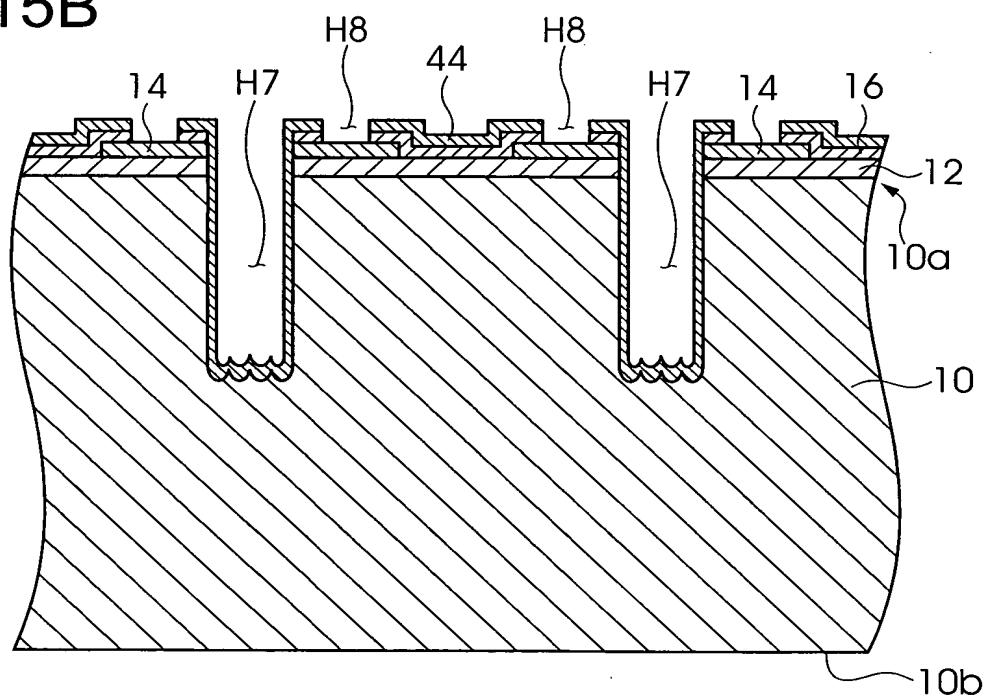


FIG.15B



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FIG.16A

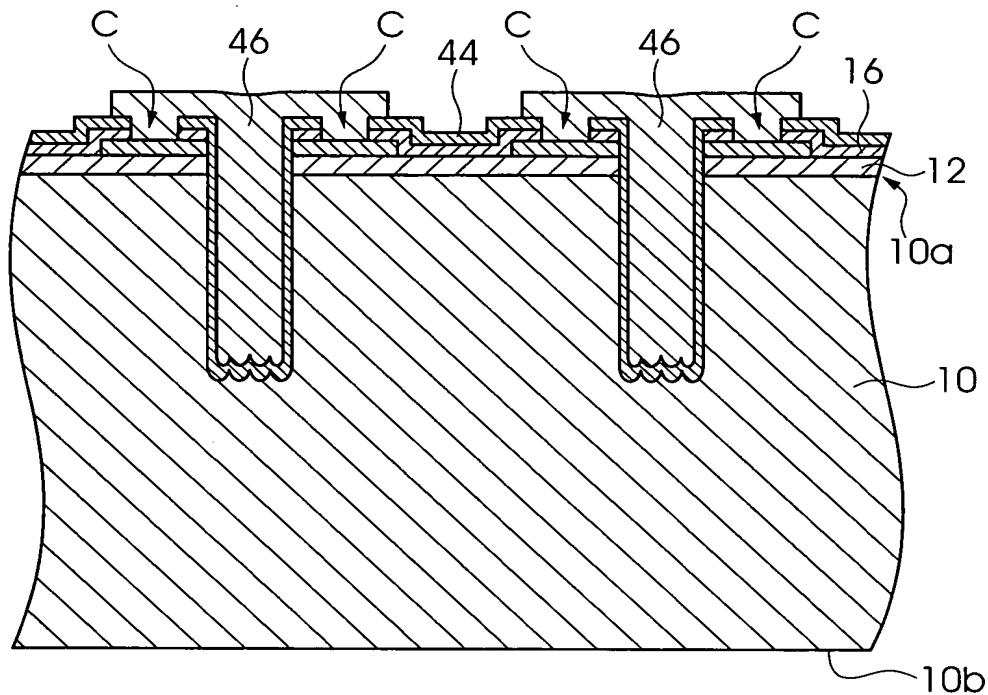


FIG.16B

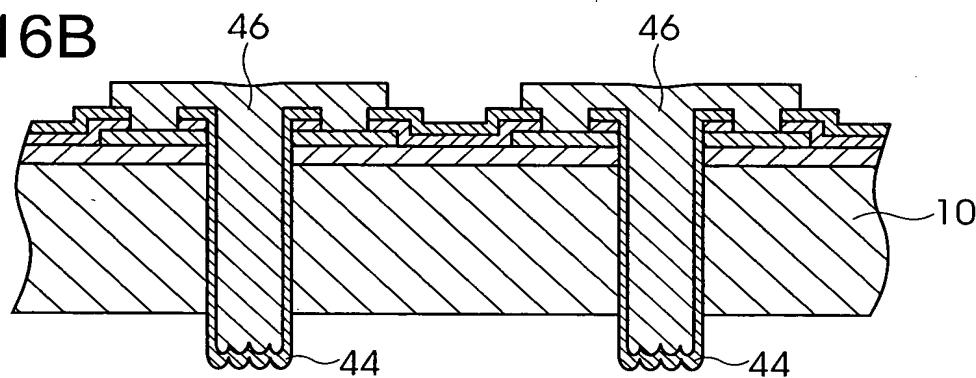


FIG.16C

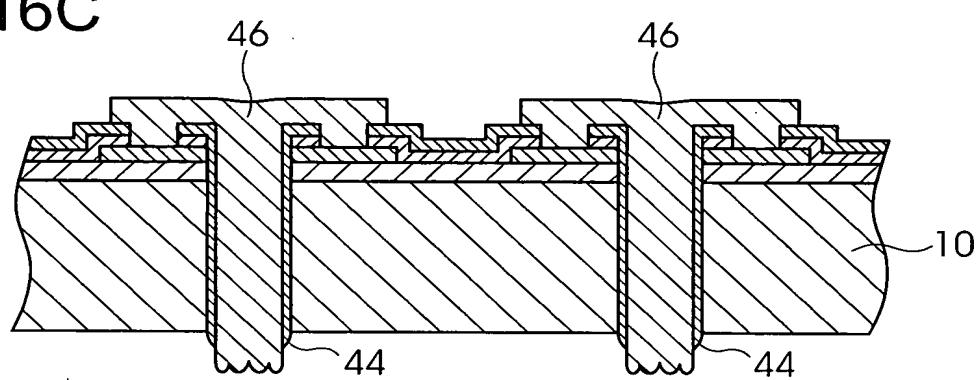
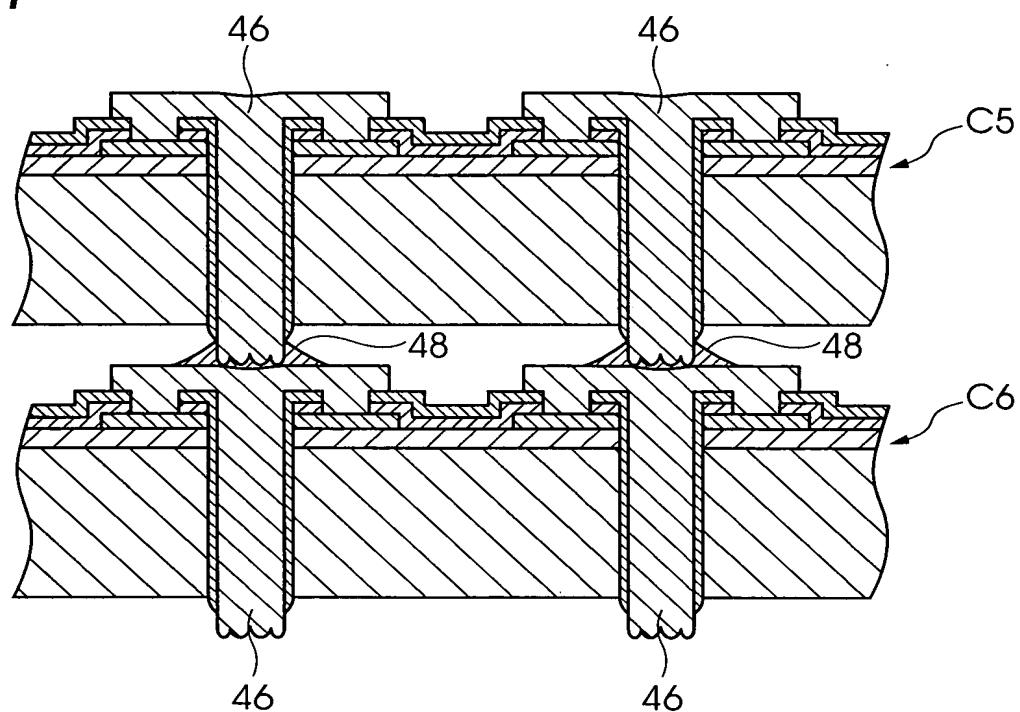


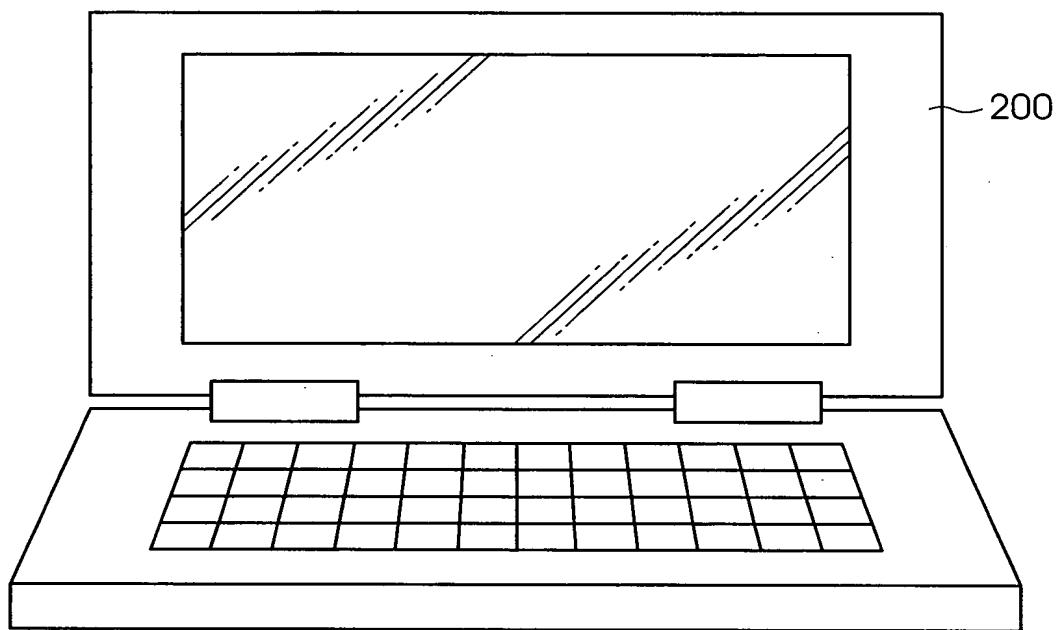
FIG.17



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## FIG.18



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Inventor(s): Yoshihide MATSUO  
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FIG.19

